

Supporting Information

for

Overcoming interface losses in organic solar cells by applying low temperature, solution processed aluminum-doped zinc oxide electron extraction layers

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S1. Parameter set for PC1D simulation

Software available at <http://www.pv.unsw.edu.au/info-about/our-school/products-services/pc1d>

Active layer:

Thickness: 0.16 μm

Material modified from program defaults

Fixed electron mobility: $3 \cdot 10^{-3} \text{ cm}^2/\text{Vs}$

Fixed hole mobility: $8 \cdot 10^{-4} \text{ cm}^2/\text{Vs}$

Dielectric constant: 3

Band gap: 0.85 eV

Intrinsic conc. at 300 K: $1 \cdot 10^{12}$

Refractive index: 1.8

Absorption coeff. from internal model

No free carrier absorption

P-type background doping: $1 \cdot 10^{15} \text{ cm}^{-3}$

No front diffusion

No rear diffusion

Bulk recombination: $T_n = T_p = 5 \mu s$

No Front-surface recombination

No Rear-surface recombination

Electron extraction layer:

Thickness: variable, 0.03-1.25 μm

Material modified from program defaults

Fixed electron mobility: $1 \cdot 10^{-3} \text{ cm}^2/\text{Vs}$

Fixed hole mobility: $1 \cdot 10^{-3} \text{ cm}^2/\text{Vs}$

Dielectric constant: 25

Band gap: 1.3 eV

Intrinsic conc. at 300 K: $1.1 \cdot 10^8 \text{ cm}^{-3}$

Refractive index: 2

Absorption coeff. from internal model

No free carrier absorption

N-type background doping: variable, $6.25 \cdot 10^{16} - 6.25 \cdot 10^{18} \text{ cm}^{-3}$

No front diffusion

No rear diffusion

Bulk recombination: $T_n = 1 \cdot 10^6 \mu s$, $T_p = 5 \mu s$

No Front-surface recombination

No Rear-surface recombination

Excitation:

Excitation mode: Transient, 200 timesteps

Temperature: 300 K

Base circuit: Sweep from 0 to 0.562 V, Step at $t = 0$

Collector circuit: Zero

Primary light source enabled

Constant intensity: 0.1 W cm⁻²

Spectrum AM 1.5 G

Secondary light source disabled

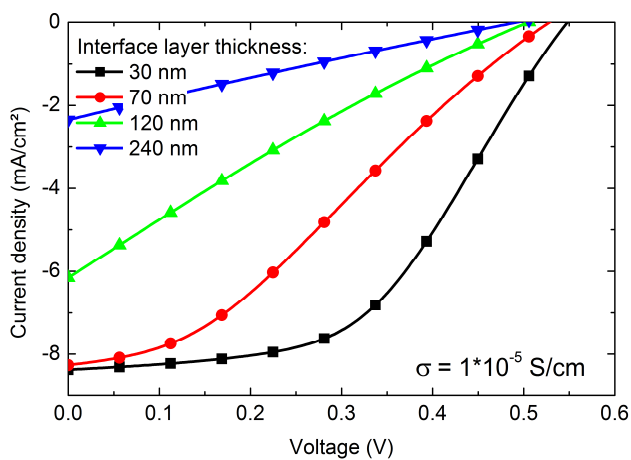


Figure S2. Low conductive interface layer induces s-shape behavior in the j-V characteristics.

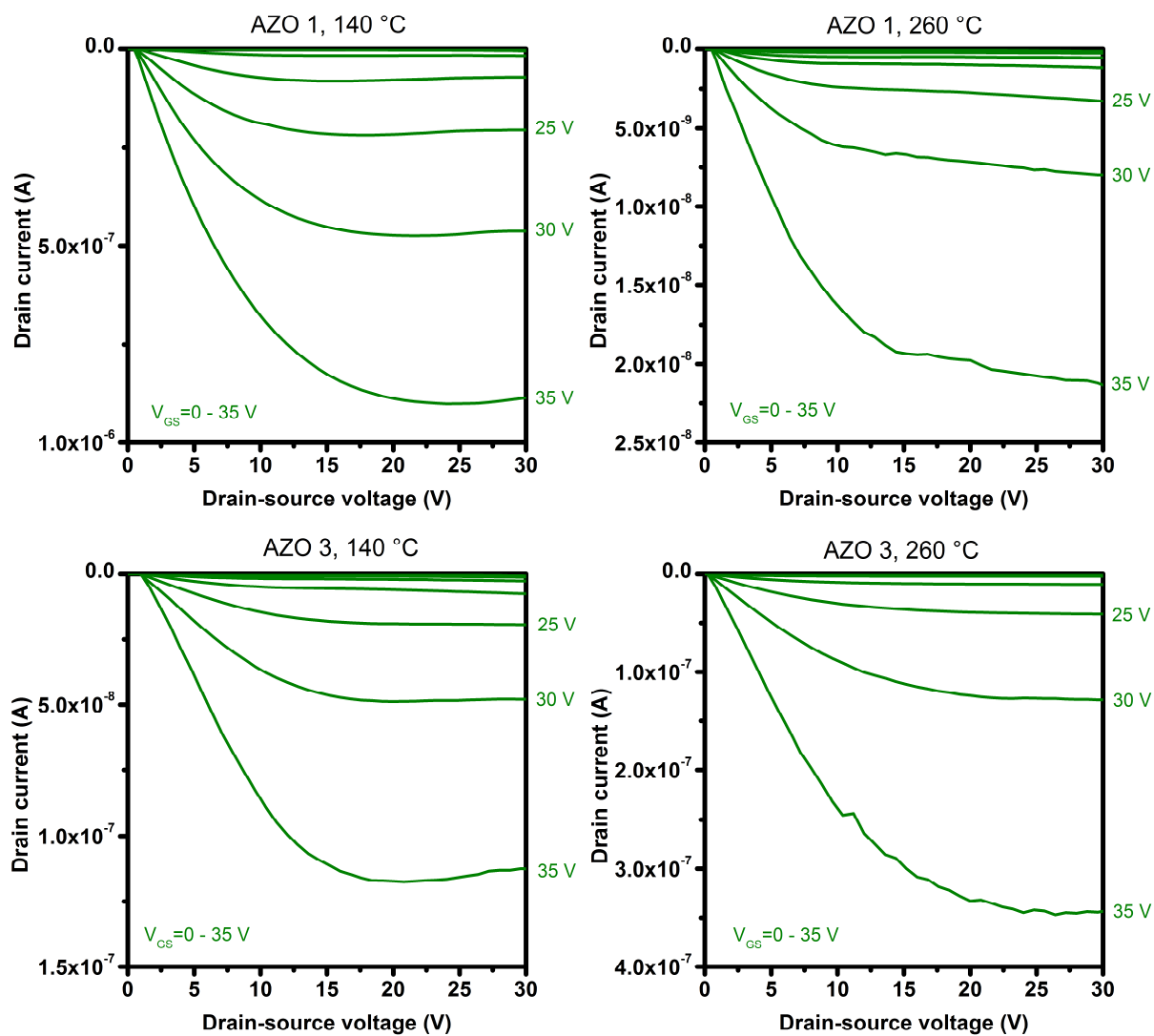


Figure S3. Output characteristics of the transistor devices with different AZO layers.

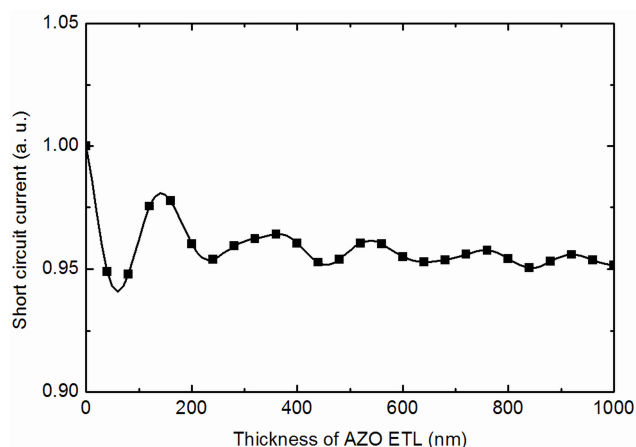


Figure S4. Optical simulation of the short circuit current with varying AZO EEL from 0-1000 nm. The simulated layer stack was Glass/ITO(400 nm)/AZO(0-1000 nm)/P3HT:PCBM(100 nm)/PEDOT:PSS(40 nm)/Ag(100 nm).

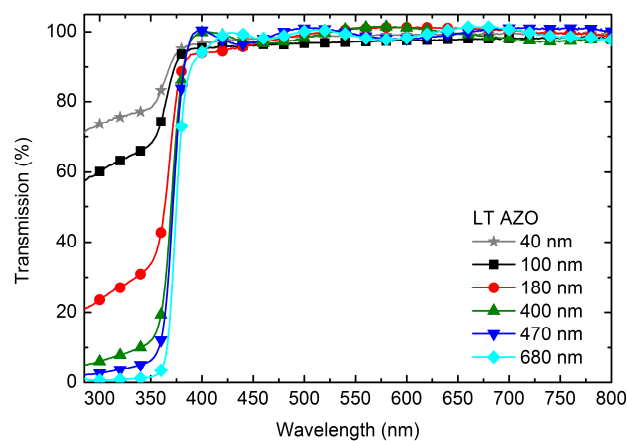


Figure S5. Optical transmission of LT AZO films with thicknesses from 40 to 680 nm excluding the glass substrate. The transmission is very high for all thicknesses in the visible wavelengths.